

19. A plasma etching apparatus according to claim 18, wherein said temperature controller controls the temperature of said jacket at a value within a range of 0°C to 100°C.

131
Cont
20. The plasma etching apparatus according to claim 17, wherein said temperature controller controls the temperature of said jacket at a value within a range of 0°C to 100°C.--

REMARKS

This preliminary amendment is submitted in the CPA in order to present new claims 13-20 reciting further features of the present invention in relation to a plasma etching apparatus including a jacket held inside the side wall of the etching chamber in an exchangeable state and controlling the temperature of the jacket so as to form a coating film on an inner surface of the jacket which is similar in composition to the etching gas used during etching treatment of the sample. The aforementioned features are described in the specification of this application at page 15, line 23 to page 16, line 2 and page 21, line 12 to page 23, line 25, for example. Applicants submit that the recited features of claims 13-20 are not disclosed in the cited art in the parent application, and favorable consideration of the newly presented claims is requested.

To the extent necessary, applicant's petition for an

extension of time under 37 CFR 1.136. Please charge any shortage in the fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account No. 01-2135 (503.34403CV4) and please credit any excess fees to such deposit account.

Respectfully submitted,



Melvin Kraus

Registration No. 22,466

ANTONELLI, TERRY, STOUT & KRAUS, LLP

MK/cee
(703) 312-6600